

WHAT IS CLAIMED IS:

1. A film formation apparatus comprising:
an evaporation source having a longitudinal direction; and
a mechanism for moving the evaporation source in a direction perpendicular to the longitudinal direction of the evaporation source.
2. An apparatus according to claim 1, wherein the evaporation source is provided with an evaporation cell having a longitudinal direction.
3. An apparatus according to claim 1, wherein the evaporation source is provided with a plurality of evaporation cells.
4. A film formation apparatus comprising:
an evaporation source having a longitudinal direction;
a mechanism for moving the evaporation source in a direction perpendicular to the longitudinal direction of the evaporation source; and
an electromagnet formed over top of the mechanism.
5. An apparatus according to claim 4, wherein the evaporation source is provided with an evaporation cell having a longitudinal direction.
6. An apparatus according to claim 4, wherein the evaporation

source is provided with a plurality of evaporation cells.

7. A film formation apparatus comprising:

a load chamber;

a conveyor chamber connected to the load chamber; and

an evaporation chamber connected to the conveyor chamber,

wherein the evaporation chamber contains an evaporation source having a longitudinal direction, and a mechanism for moving the evaporation source in a direction perpendicular to the longitudinal direction of the evaporation source.

8. An apparatus according to claim 7, wherein the evaporation source is provided with an evaporation cell having a longitudinal direction.

9. An apparatus according to claim 7, wherein the evaporation source is provided with a plurality of evaporation cells.

10. A film formation apparatus comprising:

a load chamber;

a conveyor chamber connected to the load chamber; and

an evaporation chamber connected to the conveyor chamber,

wherein the evaporation chamber contains an evaporation source having a longitudinal direction, and a mechanism for moving the evaporation source in a direction perpendicular to the

longitudinal direction of the evaporation source, and an electromagnet formed over top of the mechanism.

11. An apparatus according to claim 10, wherein the evaporation source is provided with an evaporation cell having a longitudinal direction.

12. An apparatus according to claim 10, wherein the evaporation source is provided with a plurality of evaporation cells.

13. A film formation apparatus comprising:

a load chamber;

an unload chamber; and

an evaporation chamber,

wherein said load chamber and said unload chamber and said evaporation chamber are connected in series, and

wherein the evaporation chamber contains an evaporation source having a longitudinal direction, and a mechanism for moving the evaporation source in a direction perpendicular to the longitudinal direction of the evaporation source.

14. An apparatus according to claim 13, wherein the evaporation source is provided with an evaporation cell having a longitudinal direction.

15. An apparatus according to claim 13, wherein the evaporation source is provided with a plurality of evaporation cells.

16. A film formation apparatus comprising:

a load chamber;
an unload chamber; and
an evaporation chamber,

wherein said load chamber and said unload chamber and
said evaporation chamber are connected in series, and

wherein the evaporation chamber contains an evaporation
source having a longitudinal direction, and a mechanism for
moving the evaporation source in a direction perpendicular to the
longitudinal direction of the evaporation source, and an
electromagnet formed over top of the mechanism.

17. An apparatus according to claim 16, wherein the evaporation
source is provided with an evaporation cell having a longitudinal
direction.

18. An apparatus according to claim 16, wherein the evaporation
source is provided with a plurality of evaporation cells.

19. A method of forming a thin film over a substrate while
moving an evaporation source, having a longitudinal direction, in
a direction perpendicular to the longitudinal direction of the
evaporation source.

20. A method of forming a thin film over a substrate while
moving an evaporation source, having a longitudinal direction, in
a direction perpendicular to the longitudinal direction of the

evaporation source, wherein the substrate and a shadow mask composed of a metal are in a state of contact in accordance with an electromagnet.

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